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**FAX TRANSMISSION****DATE:** November 29, 2005**PTO IDENTIFIER:** Application Number 10/725257-Conf. #1959  
Patent Number**Inventor:** Ming Jey Yang et al.**MESSAGE TO:** US Patent and Trademark Office**FAX NUMBER:** (571) 273-8300**FROM:** US NAVAL RESEARCH LABORATORY  
Joseph T. Grunkemeyer**PHONE:** (202) 404-1556**Attorney Dkt. #:** 95937US1**PAGES (Including Cover Sheet):** 3**CONTENTS:** Response to Restriction Requirement (with Traverse) (2 pages)

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Dated: 11/29/05

Signature: 

(Joseph T. Grunkemeyer)

Docket No.: 95937US1  
(PATENT)**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Patent Application of:  
Ming Jey Yang et al.

Application No.: 10/725257

Confirmation No.: 1959

Filed: December 2, 2003

Art Unit: 2822

For: NANOFABRICATION OF InAs/AlSb  
HETEROSTRUCTURES

Examiner: T. M. Thomas

**RESPONSE TO RESTRICTION REQUIREMENT**

MS Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

In a restriction requirement set forth in the Office Action mailed November 17, 2005, the Examiner required restriction among:

- I. A method of fabricating a heterostructure device, claims 1-10;
- II. A method of etching a heterostructure, claims 11-13;
- III. A method of etching a heterostructure, claim 14; and
- IV. A method of etching  $\text{Al}_x\text{Ga}_{1-x}\text{Sb}$ , claims 17 and 18.

Applicant hereby elects claims 1-10 for continued examination, with traverse. The requirement is traversed in that all the claims were already searched and examined prior to the office action of 06/03/05, thus continued examination of all claims would not present an undue burden on the PTO. The only independent claim amended in response to that office action is claim 14. Claims 4 and 6 were amended only for clarification.

In the event that a fee is required, please charge the fee to Deposit Account No. 50-0281,

Application No.: 10/725257

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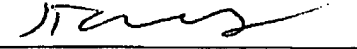
Docket No.: 95937US1

and in the event that there is a credit due, please credit Deposit Account No. 50-0281.

Dated: November 29, 2005

Respectfully submitted,

By



Joseph T. Grunkemeyer

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